

AMENDMENTS

In the Specification:

Please replace paragraph [0030] with the following:

Further, a small diameter nozzle 13 (for example, of 7 mm inner diameter) is opened in the first vacuum chamber 11, and a large diameter nozzle ~~13~~ 23 (for example, of 13 mm inner diameter) is opened in the second vacuum chamber 21, respectively, and activated species gases are brown out of the nozzles 13 and 23. At the outside of each of the vacuum chambers, and at the intermediate portion for each of the nozzles 13 and 23, a first activated species gas generator 14 and a second activated species gas generator 24 are disposed respectively. Microwaves generated by a not-illustrated microwave generator are irradiated to the intermediate portion of the nozzles in each of the activated species gas generator.

Please replace paragraph [0037] with the following:

The door 172 is opened, the first step is completed, and a SOI wafer after having been removed with unevenness (preceding SOI wafer) is detached by the transportation device 31 from the wafer table 12 and then taken into the transportation chamber 3. Then, the door 172 is closed while the door 171 is opened. A not illustrated transportation device takes out a sheet of SOI wafer from the entry chamber 4 and places it onto the emptied the first wafer table 12. The SOI wafer is held by an electrostatic chuck (not illustrated) of the first ~~water~~ wafer table 12. Then the door 171 is closed.